

# Matched Performance

## COMET RF Delivery System: cito Plus RF Generator & AGS Impedance Matching Network

### COMET Plasma Control Technologies

High performance, high reliability and precise control of plasma processes at a competitive price: these are the characteristics of the COMET RF delivery system, consisting of our AGS Impedance Matching Network and the cito Plus RF Generator.

The pair is ideal for semiconductor or industrial applications. It offers high reliability and repeatable operation over the lifetime of the product.

The AGS match offers multiple mounting possibilities and adjustable tap settings for wide tune ranges in a compact design. The full user interface and compatible pulsing with the cito Plus RF generator allows a seamless communication.

Of course both products are also available individually.

### Benefits

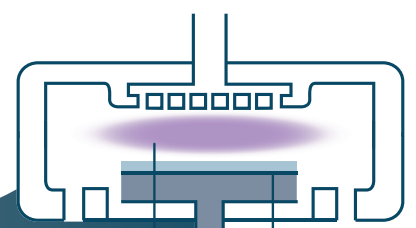
- Seamless communication between cito Plus generator and AGS match
- Perfectly matched performance
- Pulsing compatible
- Flexible and affordable solution



cito Plus RF Generator



AGS Impedance  
Matching Network



Plasma  
Wafer

**COMET**

Technology with Passion



## cito Plus Technical data

Frequency, Stability and Accuracy	13.56/60 MHz, $\pm 0.005\%$
Output Power	1 W to 1000 W
RF Accuracy	$\pm 1.0\%$ of setpoint or $\pm 0.10\%$ of max. power, whichever is greater
RF Pulsing, pulse rate	1 Hz to 100 kHz
Interfaces	Analog, RS232, Ethernet, Match control
CEX	Master/slave

### Configuration

Dimensions excl. Connectors	441 mm (width) x 500 mm (depth) x 88 mm (height)
RF Output Connector	N-type
Compliance	Compliant with all major directives and industrial standards

## AGS Technical data

Dimensions (width x depth x height)	1000 W – 3000 W: 208 mm x 324 mm x 157 mm 4000 W – 5000 W: 208 mm x 384 mm x 193 mm
Output connector	1000 W: 7-16, MC10, Mount Bar 2000 W – 5000 W: MC10, Mount Bar
Digital user Interface	Control via front panel of RF generator Digital User Interface (via host control)
AC mains input	90 to 264 VAC
Compatibility	Seamless communication with cito generator series
Cooling	Air: 10000–3000 W / Water: 4000–5000 W
Range of applications	Up to 5 kW capacitive loads Inductive load applications (ICP)
Pulsing	Pulse mode up to 10 kHz

## cito Plus RF Generator

Offers superior pulsing quality and stability making it a great choice for plasma and non-semiconductor applications.

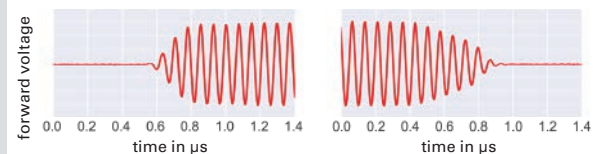
### Exceptional Pulsing Performance

#### Pulse rise time

Ultra short rise times  
< 300 ns

#### Pulse fall time

Clean falling edge of  
the pulse



### Enhanced Plasma Stability

- Forward power independent from plasma load impedance.
- Stable output power independent of cable lengths.

## AGS Impedance Matching Network

The simple match is ideal for plasma and thin-film applications in most different industries, laboratories or institutes.

The digital controller features high speed tuning, customized algorithms and synchronized pulsing.

### AGS tracks automaticall the optimum tuned position:

- Pulsing synchronized with cito RF generator
- End-to-end capacitor tuning with max. 3 s
- Standalone auto-tuning for any RF source

### Features

- Compact size with multiple mounting possibilities
- L configuration with tappable inductors
- Multiple output connector types

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V1/2019